## **TEOS Trap**



The TEOS Trap, when used as one element of a TEOS Effluent Management Subsystem<sup>™</sup>, has proven very effective in reducing particulates and increasing uptime. The TEOS Trap collects TEOS byproducts, preventing them from backstreaming into the furnace and contaminating the pump. In test cases, a greater than 20% reduction in particulates has been recorded.

Maintenance is simplified, by cleaning a single component versus many feet of piping. The large trapping capacity leads to longer preventative maintenance cycles. The high trapping efficiency provides better protection to the pump, valves and other downstream instrumentation.

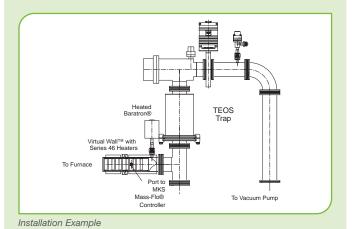
## **Product Features**

- Improve wafer yields when used as part of a TEOS Effluent Management Subsystem<sup>™</sup>
- Overall yield improvement of 2-3%
- Greater than 20% particle reduction
- Increases uptime, reduces downtime
- Easy cleaning and maintenance of Trap
- Protect vacuum pump and valves
- Low cost of ownership pay back in less than one day
- High flow conductance
- · Light weight and compact
- Available in several sizes for use with the most common lines



## **Applications**

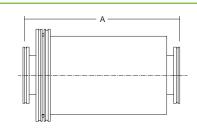
Low-pressure chemical vapor deposition using TEOS (tetraethylorthosilicate,  $Si(OC_2H_5)_4$ ) is a popular precursor for the deposition of silicon dioxide as an interlayer dielectric film. The use of TEOS does create problems on the downside of the process chamber in the vacuum pump lines. TEOS and its byproducts have a propensity to clog the vacuum pump line with solid and viscous-liquid effluent byproducts. This increases particle levels, impedes gas flow, and can cause catastrophic pump failure.



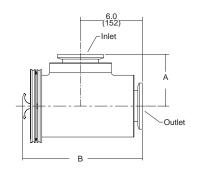


## **Specifications and Ordering Information**

Specifications			
Capacity 6'' 8''	• 1.5 lbs. (.68 kg) • 2.5 lbs. (1.14 kg)		
Flow Conductance (Viscous Flow Region)	<ul> <li>p = pressure in mTorr</li> <li>c (sscm/mTorr) = 1.4p</li> <li>slightly higher than 3" tube</li> </ul>		
Pressure Drop Across Trap	<ul> <li>Q=gas flow rate in sccm</li> <li>p=pressure in mTorr</li> <li>\D=Q/c</li> </ul>		
Typical Dry Weight 6" Angle 6" Inline 8" Angle	<ul><li>21 lbs. (9.6 kg)</li><li>13 lbs. (5.9 kg)</li><li>26 lbs. (11.8 kg)</li></ul>		
8" Inline	• 18 lbs. (8.2 kg)		
8'' Inline Flange Seals	• 18 lbs. (8.2 kg)  Part Number		
	, 0,		
Flange Seals	Part Number		
Flange Seals 6" Body, Viton	Part Number 100760516		
Flange Seals 6" Body, Viton 6" Body, Kalrez	Part Number 100760516 99T0063		
Flange Seals 6" Body, Viton 6" Body, Kalrez 8" Body, Viton	Part Number  100760516  99T0063  100760520		
Flange Seals 6" Body, Viton 6" Body, Kalrez 8" Body, Viton 8" Body, Kalrez	Part Number  100760516  99T0063  100760520  100010228		
Flange Seals 6" Body, Viton 6" Body, Kalrez 8" Body, Viton 8" Body, Kalrez Replacement Elements	Part Number  100760516  99T0063  100760520  100010228  Part Number		



	6''		8''	
Dimension A	NW50	NW80	NW80	NW100
2	11.4	12.1	12.1	12.1
	(290)	(307)	(307)	(307)



	6''		8''	
Dimension A	NW50 5.0	NW80 5.0	NW80 6.3	NW100 6.3
	(127)	(127)	(159)	(159)
Dimension B	NW50 11.5 (292)	NW80 11.5 (292)	12.0 (305)	NW100 12.0 (305)

Dimensional Drawings -

Note: Unless otherwise specified, dimensions are nominal values in inches.

TEOS Trap Ordering Information					
Body TSTRP	Body Size (X)	Port Size (-XXX)	Configuration (-X)	Flanging (-X)	Seal Type (-X)
TSTRP 8	_	<b>050</b> NW 50	<b>A</b> Angle	K KF	V Viton®
	<u> </u>	<b>080</b> NW 80	<b>I</b> Inline	M MF NW80 & 100 only	<b>K</b> Kalrez®
	NW80 & NW100 only	<b>100</b> NW100			



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Specifications are subject to change without notice.

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